

09/553,841

E0806

---

**REMARKS**

Claims 1-23 are currently pending in the subject application and are presently under consideration. Claims 1, 15 and 19 have been amended herein to further emphasize various novel aspects of the subject invention. It is noted that the amendments incorporate limitations already presented in various other pending claims; and thus, do not raise any new issues that would necessitate further reference search. A clean version of all pending claims is found on pages 3-6. A replacement paragraph for the specification is found at page 2. Favorable consideration of the subject patent application is respectfully requested in view of the comments and amendments herein.

**I. Specification**

The specification stands objected to for minor informalities. It is respectfully requested that this rejection be withdrawn for at least the following reason. A replacement paragraph has been submitted herein that obviates the informalities.

**II. Rejection of Claims 1-3, 5, 7, 10-12, 15-23 Under 35 U.S.C. §102(a)**

Claims 1-3, 5, 7, 10-12, 15-23 stand rejected under 35 U.S.C. §102(a) as being anticipated by Sanada (US Patent 6,089,763). It is respectfully requested that this rejection be withdrawn for at least the following reasons. Claims 1, 15 and 19 have been amended herein, and it is believed that such amendment renders this rejection moot.

In particular, original claims 1, 15 and 19 recite a semiconductor process visual monitoring system that comprises a semiconductor processing chamber. As disclosed in the specification of the subject application, such processing chamber can be, *inter alia*, a *develop* chamber. (See application, p. 4, ll. 20-23). Claims 1, 15 and 19 have been amended herein to further emphasize various novel aspects of the invention and recite a semiconductor process visual monitoring system that comprises a semiconductor process *develop* chamber. Sanada does not disclose, teach or suggest a *develop* chamber, as recited in the subject claims. Rather, Sanada is directed to a *coating* apparatus (See col. 24, ll. 64-67) and, as known, coating and developing chambers are separate and distinct modules within a wafer track system. Thus, Sanada does not disclose, teach or suggest the subject claims.

09/553,841

E0806

---

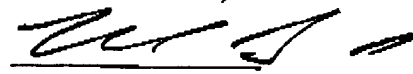
CONCLUSION

The present application is believed to be in condition for allowance in view of the above comments and amendments. A prompt action to such end is earnestly solicited.

In the event any fees are due in connection with this document, the Commissioner is authorized to charge those fees to Deposit Account No. 50-1063.

Should the Examiner believe a telephone interview would be helpful to expedite favorable prosecution, the Examiner is invited to contact applicants' undersigned representative at the telephone number listed below.

Respectfully submitted,  
AMIN & TUROCY, LLP

  
Himanshu S. Amin  
Reg. No. 40,894

AMIN & TUROCY, LLP  
24<sup>TH</sup> Floor, National City Center  
1900 E. 9<sup>TH</sup> Street  
Cleveland, Ohio 44114  
Telephone (216) 696-8730  
Facsimile (216) 696-8731



Creation date: 10-07-2004  
Indexing Officer: VDELTS - VIVIAN DELTS  
Team: OIPEBackFileIndexing  
Dossier: 09553841

Legal Date: 01-15-2004

No.	Doccode	Number of pages
1	CTFR	6

Total number of pages: 6

Remarks:

Order of re-scan issued on .....